

ABSTRACT**Control System, Lithographic Apparatus, Device Manufacturing Method,
and Device Manufactured Thereby.**

A control system for positioning means 10 comprising a PID type controller 4, or other connected in a feedback loop. The controller calculates a current for supply to the positioning means 10 according to the error between the desired value of current I_s and the measured value of current I_m . This current is converted to a voltage by amplifier 6 and
5 further modified by a feedforward voltage U_{ff} calculated using mechanical and electrical characteristics of the positioning means and desired position and/or desired derivatives of position.

Fig. 2